

Notice of References Cited	Application/Control No. 10/565,980		Applicant(s)/Patent Under Reexamination NAFTALI ET AL.	
	Examiner KARL I.E. TAMAI		Art Unit 2834	Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-			
	B	US-			
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FOREIGN PATENT DOCUMENTS

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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Xie et al., A CMOS-MEMS Micromirror with Large Out-of-Plane Actuation", 2001 ASME International Mechanical Engineering congress and Exposition, November 11-16, 2001, NY, NY, MEMS-VOL.3, IMECE2001/MEMS23813
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
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